

6/25/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Gary M. Moore

Assignee: Moore Epitaxial Inc.

Title: METHOD OF CONTROLLING GAS FLOW TO A SEMICONDUCTOR
PROCESSING REACTOR

Serial No.: Unknown Filed: Herewith

Examiner: Unknown Group Art
Unit: Unknown

Docket No.: MTEC101001

Monterey, CA
January 18, 2001

Assistant Commissioner for Patents
Box PATENT APPLICATION
Washington, D.C. 20231

PRELIMINARY AMENDMENT

Dear Sir:

Prior to examination of the above-identified application,
please amend the application as follows.

IN THE TITLE

Please change the title to --Method of Controlling Gas Flow to a Semiconductor Processing Reactor--.

IN THE SPECIFICATION

Before the first line insert --This application is a divisional of U.S. Patent Application Serial No. 09/399,611, entitled "GAS FLOW CONTROLLER SYSTEM", filed on September 20, 1999.

IN THE CLAIMS

Please cancel Claims 1-11, 22-28 without prejudice.

Please add new Claims 35-38 as follows:

--35. A method comprising: